

FORM PTO-1449 (modified)  
To: U.S. Department of Commerce  
(PW FORM PAT-1449)  
Patent and Trademark Office

Atty.  
Dkt. No.

M#

308709

P-0224.011.US

**INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT**

Applicant: GUI et al.

Appln. No.: NOT ASSIGNED

Filing Date: March 18, 2004

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of

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Examiner: NOT  
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**U.S. PATENT DOCUMENTS**

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	3,752,589	08/1973	Kobayashi			
	BR	4,046,985	09/1977	Gates			
	CR	4,408,875	10/1983	Majima			
	DR	4,798,470	01/1989	Moriyama et al.			
	ER	4,897,553	01/1990	Nishi			
	FR	4,952,060	08/1990	Ina et al.			
	GR	5,241,188	08/1993	Mizutani			
	HR	5,298,988	03/1994	Everett et al.			
	IR	5,361,132	11/1994	Farn			
	JR	5,530,552	06/1996	Mermagen et al.			
	KR	5,552,892	09/1996	Nagayama			
	LR	5,621,813	04/1997	Brown et al.			
	MR	5,821,549	10/1998	Talbot et al.			
	NR	5,843,831	12/1998	Chung et al.			
	OR	5,874,190	02/1999	Tanaka			
	PR	5,894,530	04/1999	Wilt			
	QR	5,929,997	07/1999	Lin			
	RR	5,936,711	08/1999	Miyai et al.			
	SR	5,978,069	11/1999	Kato			
	TR	5,985,764	11/1999	Lin et al.			

**FOREIGN PATENT DOCUMENTS**

		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Enclosed	No	Enclose	No
	UR	0 756 207 A3	01/1997	Europe					
	VR	1-164032	06/1989	Japan					
	WR	3-246923	11/1991	Japan					
	XR	10-187937	07/1998	Japan					
	YR	10-209030	08/1998	Japan					
	ZR	11-340120	12/1999	Japan					

**OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

	AAR	Everett et al., "Aligning lithography on opposite surfaces of a substrate," <i>Applied Optics</i> , Vol. 31, No. 34, pp. 7292-7294, 1992.			
	BBR				

Examiner

Date Considered:

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	CCR 6,141,108	10/2000	Kida et al.			
	DDR 6,262,793	07/2001	Sasaya et al.			
	EER 6,376,329	04/2002	Sogard et al.			
	FFR 6,525,805	02/2003	Heinle			
	GGR					
	HHR					
	IIR					
	JJR					
	KKR					
	LLR					
	MMR					
	NNR					
	OOR					

## **FOREIGN PATENT DOCUMENTS**

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					Enclosed	No	Enclose	No
	PPR							
	QQR							
	RRR							
	SSR							
	TTR							
	UUR							

## **OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

VVR	Katagiri et al., "Novel Alignment Technique for 0.1-μm Lithography Using the Wafer Rear Surface and Canceling Tilt Effect," <i>Optical Engineering</i> , Vol. 32, No. 10, pp. 2344-2349, 1993.			
WW	Patent Abstracts of Japan, JP11340120, published December 1999.			
XXR	Patent Abstracts of Japan, JP05144702, published June 1993.			
YYR	Patent Abstracts of Japan, JP3246923, published November 1991.			
ZZR	Patent Abstracts of Japan, JP1164032, published June 1989.			
AAA				
BBB				

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